

The 103rd Microoptics meeting DOE/Microoptics on Diffraction



Sponsored by: Microoptics Group, Optical Society of Japan, JSAP

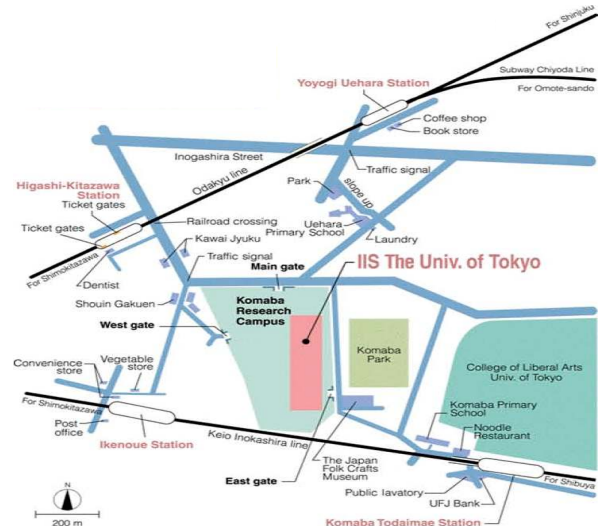
Date: March 8th (Thu.), 2007, 10:00–17:00

Location: Convention Hall, Institute of Industrial Science,
The University of Tokyo
(4-6-1, Komaba, Meguro-ku, Tokyo)

<http://www.iis.u-tokyo.ac.jp/english/map/index.html>

Access: 10 min. walk from Komaba Todaimae Station
(Keio Inogashira Line)

12 min. walk from Higashi Kitazawa Station
(Odakyu Line)



Program

- 10:00–10:10 Opening Remarks
- 10:10–10:40 Fundamentals of Grating for Device Applications Kiyoshi Yokomori (Ricoh)
- 10:40–11:10 What Can We Get by Stacking Diffraction Gratings? Hiroyuki Ichikawa (Ehime Univ.)
- 11:10–11:40 Design of Subwavelength Diffractive Optical Elements Using Genetic Algorithm
Kenichi L. Ishikawa (Univ. of Tokyo)
- 11:40–13:00 < Lunch Break >
- 13:00–13:30 Photo-Curable Organic/Inorganic Nanocomposites for UV Imprinting Technology
Hiroshi Mataki (KRI)
- 13:30–14:00 High-Speed and Large-area Optical Nanofabrication by Thermal Lithography Technique
Kazuma Kurihara, Yuzo Yamakawa, Takashi Nakano and Junji Tominaga (AIST)
- 14:00–14:30 Super Wide-Band Polymeric Quarter Wave Plates Fabricated by Nanoimprint Technologies
Osamu Masuda, Masahiro Morikawa, Hiroshi Miyakoshi, Makiko Imae and Motohiro Yamada
(Konica Minolta Technology Center)
- 14:30–15:00 Holographic Femtosecond Laser Processing Yoshio Hayasaki (Univ. of Tokushima)
- 15:00–15:20 < Break >
- 15:20–15:50 High Dispersion Volume Phase Holographic (VPH) Grism for Subaru Telescope
Kashiko Kodate (Japan Women's Univ.)
- 15:50–16:20 Read/Write Pickup for Dual-Layer 2x BD, DVD and CD
Toshiyasu Tanaka, Kousei Sano, Kenji Matsumura, Keiichi Matsuzaki, Hidenori Wada, Kanji Wakabayashi and
Yoshiaki Komma (Matsushita Electric Industrial)
- 16:20–16:50 Optical Filters Using Si Subwavelength Grating or MEMS Kazuhiro Hane (Tohoku Univ.)
- 16:50–17:00 Closing Remarks

Registration (On Site Only): General ¥4,000 / Student ¥1,000

Steering Members: S. Nakatsuka (Hitachi), R. Katayama (NEC), K. Yamamoto (Matsushita Electric Industrial),
S. Kittaka (Nippon Sheet Glass) and S. Kawai (Polytechnic Univ.)

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Microoptics Group: Representative K. Iga, Organizing Chair K. Goto, Steering Chair H. Nakajima, Vice-Chair Y. Kokubun

The program of the meeting will be updated in the web page of Microoptics Group. (<http://www.comemoc.com/>)